

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Henry A. Hill Art Unit: 2877

Serial No.: 10/616,504 Examiner:

Filed : July 8, 2003

Title : CYCLIC ERROR COMPENSATION IN INTERFEROMETRY SYSTEMS

## Mail Stop Amendment

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Please consider the references listed on the attached form PTO-1449. Copies of non-patent references are enclosed.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office Action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: (0/78/04

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\*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).

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I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Dox 1459, Alexandria, VA 22313-1450.

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U.S. Department of Commerce Patent and Trademark Office Attorney's Docket No. 09712-330001

Application No. 10/616,504

Information Disclosure Statement by Applicant NOV 0'1 2004 Use several sheets if necessary)

Henry A. Hill

July 8, 2003

Applicant

Filing Date

Group Art Unit 2877

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Exa	miner	Signature

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EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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U.S. Department of Commerce Patent and Trademark Office

10/19/2004

04/25/2002

Attorney's Docket No. 09712-330001

Application No. 10/616,504

Disclosure Statement

by Applicant (Use several sheets if necessary)

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Henry A. Hill

Applicant

Group Art Unit 2877

(37 CFR §1.68(b))

Examiner

Initial

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 Publication Date
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 Subclass
 Filing Date If Appropriate

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 Hill et al.
 Isshiki et al.
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